Express Mail No.: <u>EV374985861US</u>

**PATENT** 

H0003762-1170

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Chien-Wei Li

Serial No.: Filed herewith Filing Date: Filed herewith

For: ATOMIC LAYER DEPOSITION FOR

**TURBINE COMPONENTS** 

## **COMMENTARY RE INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In accordance with 37 CFR §1.56, and in recognition of his duty to disclose to the United States Patent and Trademark Office relevant information known to be material to patentability, Applicant identifies the prior art listed on the attached Information Disclosure Statement (Form PTO-1449). The statement is not a representation that all of the information cited is necessarily effective as prior art against the application. Only copies of non US patents and patent applications are enclosed, if any.

Applicant respectfully requests that the disclosed reference be made of record in the subject application.

Respectfully submitted,

Michael A. Shimokaji, Reg. No. 32,303 Robert Desmond, Reg. No. 38,430

Attorneys for Applicant

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PTO/SB/08A (10-01)

Approved for use through 10/31/2002, OMB 0651-0031

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Substitute for form 1449A/PTO			Complete if Known		
			Application Number	filed herewith	
INFORMATION DISCLOSURE			Filing Date	filed herewith	
STA	TEMENT BY	APPLICANT	First Named Inventor	LI, Chien-Wei	
			Group Art Unit		
(use	(use as many sheet as necessary)		Examiner Name		
Sheet	1	of 2	Attorney Docket Number	H0003762-1170	

				U.S. PATENT	DOCUMENTS	
		Do	cument Number			Pages, Columns, Lines
Examiner	Cite	Numb	er - Kind Code² (if	Publication Date	Name of Patentee or Applicant	Where Relevant
Initials*	No. <sup>1</sup>	known	·	MM-DD-YYYY	of Cited Document	Passages or Relevant Figures Appear
	1	US-	6,585823	07-01-2003	VAN WIJCK	
	2	US-	2003-0059633 A1	03-27-2003	ACKERMAN et al.	
	3	US-	2003-0026989 A1	02-06-2003	GEORGE et al.	
	4	US-	6,503,330 B1	01-07-2003	SNEH et al.	
	5	US-	6,492038 B1	12-10-2002	RIGNEY et al.	
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	FO	REIGN PATENT	OCUMENTS		
	Foreign Patent Document			Pages, Columns, Lines	
Cite No. 1	Country Code <sup>3</sup> 'Number <sup>4</sup> Kind Code <sup>5</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Where Relevant Passages or Relevant Figures Appear	Τ*
13	WO 03/058734 A1	07-17-2003	CHAN, Chung M., et al.		<b>.</b>
		Cite No. 1 Country Code 3 Number 4 Kind Code 4 (if known)	Foreign Patent Document  Cite No. 1 Country Code 3 Number 4 Kind Code 5 (If known)  Publication Date MM-DD-YYYY	Cite No. 1  Country Code 3 Number 4 Kind Code 5 (if known)  Publication Date MM-DD-YYYY  Applicant of Cited Document	Foreign Patent Document  Cite No. 1  Country Code 3 Number 4 Kind Code 3  (if known)  Publication Date MM-DD-YYYY  Publication Date MM-DD-YYYY  Applicant of Cited Document  Pages, Columns, Lines  Where Relevant Passages or Relevant Figures Appear

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<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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<sup>&</sup>lt;sup>1</sup> Unique citation designation number. <sup>2</sup> See attached Kinds of U.S. Patent Documents. <sup>3</sup> Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup> For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent documents. <sup>5</sup>Kind of document by the appropriate symbols as indicated on the document under WIPO Standard St.16 if possible. <sup>6</sup>Applicant is to place a check mark here if English language Translation is attached.

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			Group Art Unit		
(use	e as many sheet	as necessary)	Examiner Name		
Sheet	2	of 2	Attorney Docket Number	H0003762-1170	

		OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No. 1	Include name of the author (in CAPITAL LETTERS), title of the article (when Appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T 2
	14	RITALA, Mikko, et al., Atomic Layer Deposition, Handbook of Thin Film Materials, October 2001, Volume 1, Chapter 2; San Diego, U.S.	
	15	SNEH, Ofer, et al.; Thin Film Atomic Layer Deposition Equipment for Semiconductor Processing; Thin Solid Films 402 (2002); pp. 248-261	

Examiner	Date
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